

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Venkat Selvamanickam, et al.

Title: APPARATUS FOR AND METHOD OF CONTINUOUS HTS TAPE
BUFFER LAYER DEPOSITION USING LARGE SCALE ION BEAM
ASSISTED DEPOSITION

App. No.: 10/609,250 Filed: June 26, 2003

Examiner: Ram N. Kackar Group Art Unit: 1792

Customer No.: 34456 Confirmation No.: 7760

Atty. Dkt. No.: 1014-SP101-US

MS AMENDMENT
Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

RESPONSE TO FINAL OFFICE ACTION

Dear Sir:

In response to the Final Office Action mailed March 23, 2009, please amend the above-identified application as follows:

The Claim Amendments begin on page 2.

The Remarks begin on page 7.